JUN 0 1 2002

#12/A 2814 6-11-02 # Moush

## PARMAPHE UNITED STATES PATENT AND TRADEMARK OFFICE

In re t	the Application of	)	
Kazuo MAEDA		) Examiner: Quach	
Serial No.: 09/519,599		) Art Unit: 2814	v
Filed: March 6, 2000		)	TECHN
For:	METHOD AND APPARATUS FOR FORMING AN INTERLAYER INSULATING FILM AND SEMICONDUCTOR DEVICE	) ) ) )	RECEIVEL JUN-7 2002 TECHNOLOGY CEALER
RESPONSE TO OFFICE ACTION OF DECEMBER 4, 2001			) ? ? 280

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

Responsive to the office action of December 4, 2001, please amend the captioned application as follows:

## IN THE SPECIFICATION:

Please substitute the attached "Substitute Specification and Abstract" for the originally fled specification and abstract.

## IN THE CLAIMS:

Please rewrite claims 1, 5, 6 and 7 as follows: